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Rosalie A. Centeno
Rosalie A. Centeno, Secretary

In the application of: Ulrich Speh

Serial Number: 10/501,256

Filing Date: July 8, 2004

For: APPARATUS AND METHOD FOR TREATING DISC-SHAPED
SUBSTRATES

Commissioner of Patents

Alexandria, Virginia 22313-1450

INFORMATION DISCLOSURE STATEMENT

In accordance with 37 CFR § 1.56, Applicant wishes to call the attention of the Examiner to the following reference:

- 1) DE 198 30 162
- 2) US 2001/0037858
- 3) US 6,322,009
- 4) WO 99/16109
- 5) US 6,167,893
- 6) JP 04186626
- 7) US 6,225,235
- 8) JP 60079724
- 9) DE 198 55 654
- 10) DE 91 14 767.0

Reference 1 is discussed in the instant specification for this application on page 1.

References 2 - 7 have been cited in the International Search Report and are submitted to provide the Examiner easy access to said references.

Reference 8 is in the English language and therefore needs no further discussion as to its relevance.

Reference 9 discloses that tips (200) are secured at the ring periphery in a mutual space. Each tip protrudes radially inwards to the ring and has several side faces, tapering towards an individual, continuous rotation surface located at one tip point inside the ring. The point is radially most remote from the ring so that a cross-section comprises several side faces and the rotation surface in a ring plane also contains two segments on lines, intersecting at sharp angles, as well as an arc of a concave ellipse, with the arc starting at line segment and ends at the other one most remote from the ring. Independent claims are included for a plasma treatment device and an integrated circuit.

Reference 10 discloses an invention that is a substrate holding apparatus for rotatably drivable substrate, in particular for rectangular substrates. The holding apparatus is provided with a centering apparatus that can be actuated by the rotation of the holding apparatus.

Copies of the referenced documents are submitted herewith along with the form PTO-1449.

It is respectfully requested that any fees required and not enclosed herewith or any shortages in any fees be charged to Deposit Account 02-1653.

Consideration of the foregoing in relation to this application is respectfully requested.

Respectfully submitted,



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RWB/rac
Enclosures: PTO 1449/references



INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Complete if Known	
		Application Number	10/501,256
		Filing Date	July 8, 2004
		First Named Inventor	Ulrich Speh et al
		Group Art Unit	
		Examiner Name	
		Attorney Docket No.	SCP-3531

U. S. PATENT DOCUMENTS							
Examiner Initials	Cite No.	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date
	2	2001/0037858	11/8/2001	Taniyama et al			5/4/2001
	3	6,322,009	11/27/2001	Subramanian et al			10/29/1999
	5	6,167,893	1/2/2001	Taatjes et al			2/9/1999
	7	6,225,235	5/1/2001	Kunze-Concewitz			2/18/2000

FOREIGN PATENT DOCUMENTS								
Examiner Initials	Cite No.	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	1	DE 198 30 162	20 Jan 2000	Germany			X	
	4	WO/991610	01 Apr 1999	WIPO			X	
	6	JP 04186626	03 Jul 1992	Japan			X	
	8	JP 60079724	07 May 1985	Japan			X	
	9	DE 198 55 564	15 Jun 2000	Germany			X	
	10	DE 91 14 767	06 May 1993	Germany			X	

OTHER PRIOR ART & NON PATENT LITERATURE DOCUMENTS		
Examiner Initials	Cite No.	

Examiner		Date	
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10/29/2004